

**APPARATUS AND METHODS FOR PREVENTING ROTATIONAL
SLIPPAGE BETWEEN A VERTICAL SHAFT AND A SUPPORT STRUCTURE
FOR A SEMICONDUCTOR WAFER HOLDER**

Abstract of the Disclosure

A substrate support assembly positively secures a substrate holder support to a rotation shaft with respect to rotationally applied forces. A substrate holder support is configured to have an opening in a socket into which, when aligned with an indentation in the rotational shaft to form a passage, a retaining member is removably inserted to engage both the socket opening and the shaft indentation. Methods of rotating a substrate while minimizing rotational slippage of the substrate holder support with respect to the shaft are also provided.

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